

Acquisition of All Shares of Yamanaka Hutech Corporation

May 16th, 2024

Executive Summary



Entry into the Deposition field, which is driving the complexity of semiconductor structures.

- YHC, which has a proven track record of in ALD materials for cutting-edge semiconductor devices, is now part of JSR Group.
- Aiming for semiconductor materials leadership, adds precursor to product portfolio
- A common culture that emphasizes innovation, technology and quality to contribute to customer value
- Strengthen YHC's product development resources and provide global sales and technical support infrastructure
- Business expansion through expansion of customer base and product expansion into new Si-based and metal-based materials

Investment Overview



Case summary	Agreement reached to acquire all shares of Yamanaka Hutech Corporation and make it a wholly owned subsidiary of JSR
Subject company	 Yamanaka Hewtech Corporation (President: Tsuyoshi Moriwaki) Manufacture and sale of high-purity chemicals for semiconductor materials, optical fiber materials, etc. HQ: 29, Shimogamo Matsubara-cho, Sakyo-ku, Kyoto-shi, Kyoto Established: November 1, 1967 Number of employees: 76 (As of June 2023)
Schedule	Signing: May 15, 2024 Closing: Aug 2024 (Plan)

YHC Products



Fine Chemi cals

CVD materials

- Al wiring protection film, interlayer dielectric, Low-K film and gas barrier film
- TEOS/TEPO/TMPO/TEB/HMDS/HMSDO, etc.
- **ALD** materials
- Si-based strategic products
- Diffusion materials

Materials for Power Devices

Materials for Resist

- POCl3/BBr3/SiCl4/Ga-based materials, etc.
- Si-based strategic products

MEMS

 Contract service processing to various MEMS sensors, inkjet, medical devices, etc.

Coatings

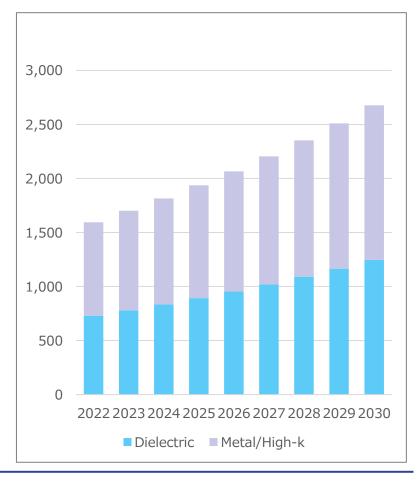
Development and sales of coatings for spray application

Contract service of precision spray coatings

Silicon Glass Wafer

 Sales of various substrates of 2-12 inch size silicon wafers and processing services for various wafers

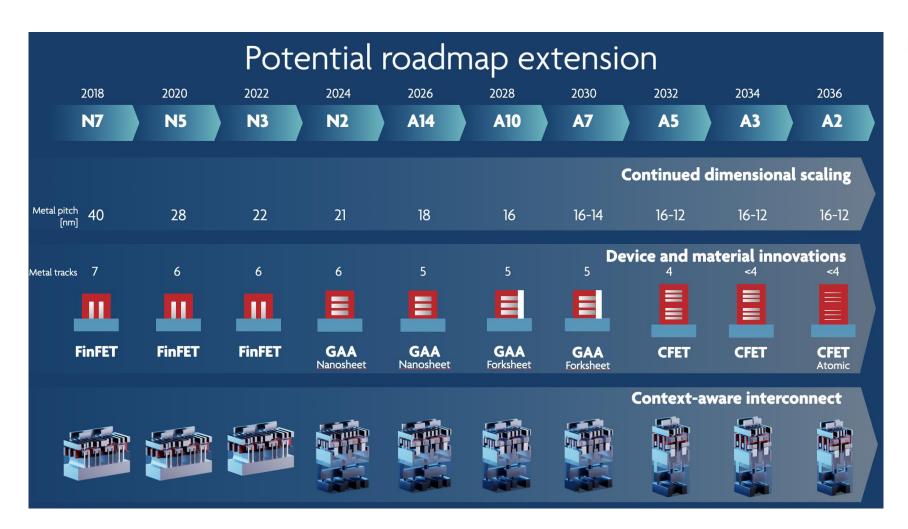
(Reference) Estimated precursor market size (MUSD)



Source: JSR estimates based on TECHCET report

Device Trends and Key Technologies





□ Driving Force of Device Evolution

1. Scaling

Contribution to
 miniaturization by EUV
 resists including metal
 resists and multilayer
 material lineup

2. Complexity



npria

 Precursor, a key material in the deposition process responsible for structural complexity, is added to our portfolio.

3.3D

Heterogeneous Integration